

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re United States Patent Application of:)	Docket No.:	020732-110.694
Applicant:)	Examiner:	AHMED, Shamim
Application No.:)	Art Unit:	1792
Date Filed:)	Confirm. No.:	5492
Title:)	Customer No.:	
COMPOSITION USEFUL FOR REMOVAL OF BOTTOM ANTI-REFLECTION COATINGS FROM PATTERNEDE ION- IMPLANTED PHOTORESIST WAFERS			

24239

**RESPONSE TO THE OCTOBER 12, 2007 OFFICE ACTION, SUPPLEMENTAL
INFORMATION DISCLOSURE STATEMENT, DECLARATION UNDER 37 CFR §1.131
AND REQUEST FOR CONTINUED EXAMINATION IN UNITED STATES PATENT
APPLICATION NO. 10/807,858**

Mail Stop AF
Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

This responds to the October 12, 2007 Office Action in the above-identified application.

The claims of the application are set out in the following **Section I (The Claims)**.

Remarks addressing the substance of the October 12, 2007 Office Action are set out in the **Section II (Remarks)** hereof.